Nanofabrication with RAITH EBL and FIB equipment
Satellite Workshop - ImagineNano 2015 Conference, Bilbao / Spain
Bilbao Exhibition Centre
Tuesday, 10th March 2015 from 15:00 to 18:30

Agenda:

First Session : Nanofabrication with electrons

15:00  Welcome
Vincent Morin, Raith GmbH, Dortmund, D

15:05  News on Products & recent Application highlights
Andreas Remscheid, Raith GmbH, Dortmund, D

15:40  Electron beam lithography: spintronics and nano-optics applications
Luis E. Hueso, CIC NanoGUNE, Donostia-San Sebastian, E

16:10  Raith EBL Applications & Nanofabrication Methods
Mike Butler, Raith B.V., Best, NL

16:40  Electron Beam Lithography – Applications at Fraunhofer HHI
Ralf Steingrueber, Fraunhofer Heinrich Hertz Institute, Berlin, D

17:10  Coffee Break

Second Session : Nanofabrication with ions

17:30  Ion column and Source Technology employing Gallium and New Ion Species for Advanced FIB Nanofabrication
Vincent Morin, Raith GmbH, Dortmund, D

18:00  High precision nanofabrication for light management at nanoscale
Saulius Juodkazis, Centre for Micro-Photonics, Swinburne University of Technology, AU

18:30  Wrap Up, Final Words, Questions & Remarks